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## TRANSMITTAL FORM

(to be used for all correspondence after initial filing)

Total Number of Pages in This Submission

Application Number	10/525,297
Filing Date	02/15/2005
First Named Inventor	James S. Im
Art Unit	2811
Examiner Name	
Attorney Docket Number	A3541-PCT-USA (070050.2717)

### ENCLOSURES (Check all that apply)

<input type="checkbox"/> Fee Transmittal Form	<input type="checkbox"/> Drawing(s)	<input type="checkbox"/> After Allowance Communication to TC
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<input type="checkbox"/> After Final	<input type="checkbox"/> Petition to Convert to a Provisional Application	<input type="checkbox"/> Proprietary Information
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### SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT

Firm Name	Baker Botts LLP	Customer No.	21003
Signature			
Printed name	Paul A. Ragusa		
Date	10/11/2005	Reg. No.	38,587

### CERTIFICATE OF TRANSMISSION/MAILING

I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on the date shown below:

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This collection of information is required by 37 CFR 1.5. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.11 and 1.14. This collection is estimated to 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**



Applicants : James S. Im Customer No.: 21003  
Serial No. : 10/525,297 Examiner : Not yet assigned  
Filed : 02/15/2005 Group Art Unit: 2811  
For : PROCESS AND SYSTEM FOR LASER CRYSTALLIZATION PROCESSING  
OF FILM REGIONS ON A SUBSTRATE TO MINIMIZE EDGE AREAS, AND  
STRUCTURE OF SUCH FILM REGIONS

## INFORMATION DISCLOSURE STATEMENT

I hereby certify that this paper is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

October 11, 2005

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**Date of Deposit**

Paul A. Ragusa

Attorney Name

38,587

Patent Reg. No.

Signature

– October 11, 2005

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicants bring to the attention of the Examiner the documents listed on the attached Form PTO 1449 and respectfully request that the listed documents be considered by the Examiner and made of record in the above-captioned application. Copies of all U.S. Patents and Applications are not enclosed pursuant to the waiver of 37 CFR 1.98 (a)(2)(i) for all applications filed after June 30, 2003. However, copies of all of the other documents listed on the Form PTO-1449 are enclosed herewith.

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This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed documents are material or constitute "prior art." If the Examiner applies the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of the documents.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should the documents be applied against the claims of the present application.

This Information Disclosure Statement is being before the mailing of a First Office Action. Therefore, applicants believe no fee is due. If any additional fee is due, or if any overpayment has been made, the Commissioner is authorized to charge any such fee or credit any overpayment, to our Deposit Account No. 02-4377.

Respectfully submitted,

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By: 

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<b>Form PTO-1449 U.S. Department of Commerce (REV. 2-82) Patent and Trademark Office</b> <b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> <small>(Use several sheets if necessary)</small>		Atty. Docket No. A35413-PCT-USA (070050.2717)	Serial No. 10/525,297
		Applicant James S. Im	
		Filing Date 02/15/2005	Group 2811
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### U.S. PATENT DOCUMENTS

Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
	1	3632205	01/04/1972	Marcy
	2	4234358	11/18/1980	Celler et al.
	3	4309225	01/05/1982	Fan et al.
	4	4382658	05/10/1983	Shields et al.
	5	4456371	06/1984	Lin
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NY02:531132.1

Examiner

Date Considered

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	47	6120976	09/2000	Treadwell et al.
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Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
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		Applicant James S. Im	
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Exam. Initial.	No.	Document No.	Issue/Publication Date	Applicant(s)
	130	6582827	06/24/2003	Im
	33	6830993	12/14/2004	Im et al.

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### FOREIGN PATENT DOCUMENTS

Exam Initial	No.	Document No.	Publication Date	Country	Translation	
					Yes	No
	90	681316	08/11/1995	EP		
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	93	2338343	12/15/1999	GB		
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	95	2338342	12/15/1999	GB		
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	97	6252048	09/09/1994	JP		<u>No</u>
	98	6283422	10/07/1994	JP		<u>No</u>
	99	7176757	07/14/1995	JP		<u>No</u>
	100	11064883	03/05/1999	JP		<u>No</u>
	101	04033327		JP		<u>No</u>
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	103	62181419	08/08/1987	JP		
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INFORMATION DISCLOSURE STATEMENT BY APPLICANT			
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Exam Initial	No.	Document No.	Publication Date	Country	Translation	
					Yes	No
	105	9931719	06/24/1999	WO		<u>No</u>
	106	0014784	03/16/2000	WO		
	107	0118854	03/15/2001	WO		
	108	0118855	03/15/2001	WO		
	109	0171786	09/27/2001	WO		
	110	02031869	04/18/2002	WO		
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	112	9745827	12/04/1997	WO		
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	114	03046965	06/05/2003	WO		
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	119	04017382	02/26/2004	WO		
	120	04017381	02/26/2004	WO		

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Exam Initial	No.	Document No.	Publication Date	Country	Translation	
					Yes	No
	121	04017380	02/26/2004	WO		
	122	04075263	08/19/2003	WO		

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Exam Initial	No.	<b>OTHER DOCUMENTS (including Author, Title, Date, Pertinent Pages, Etc.)</b>	
	132	Im et al., "Controlled Super-Lateral Growth of Si Films for Microstructural Manipulation and Optimization", Phys. Stat. Sol. (a), vol. 166, p. 603 (1998).	
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	151	E. Fogarassy et al., "Pulsed Laser Crystallization of Hydrogen-Free a-Si Thin Films for High-Mobility Poly-Si TFT Fabrication," 56 Applied Physics A--Solids and Surfaces, pp. 365-373 (1993).	
	152	Y. Miyata et al., "Low-Temperature Polycrystalline Silicon Thin-Film Transistors for Large-Area Liquid Crystal Display," 31 Japanese J. of Applied Physics Part 1--Regular Papers Short Notes & Review Papers, pp. 4559-62 (1992).	
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	154	Im <i>et al.</i> , "On the Super Lateral Growth Phenomenon Observed in Excimer Laser-Induced Crystallization of Thin Si Films," <i>Appl. Phys. Lett.</i> , Vol. 64 (17), p. 2303 (1994).	
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